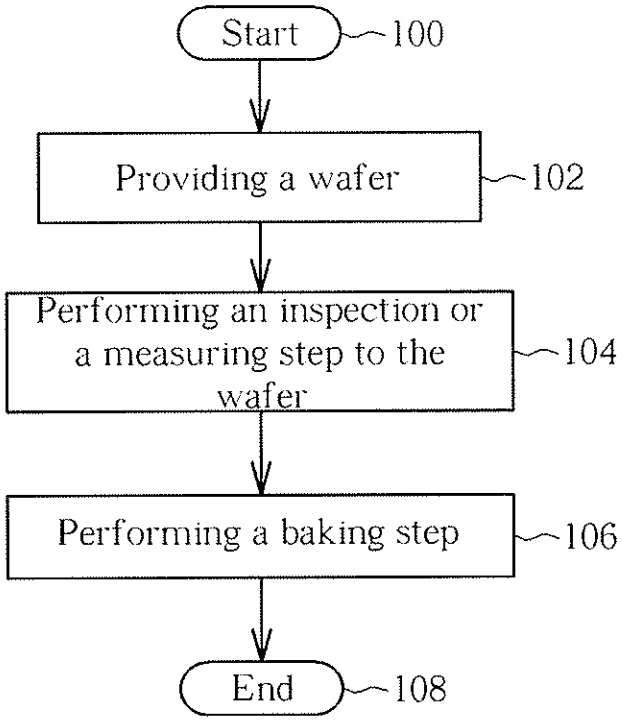

Start
100
Providing a wafer
102
Performing an inspection or a measuring step to the wafer
104
Performing a baking step
106
End
108

FIG. 1

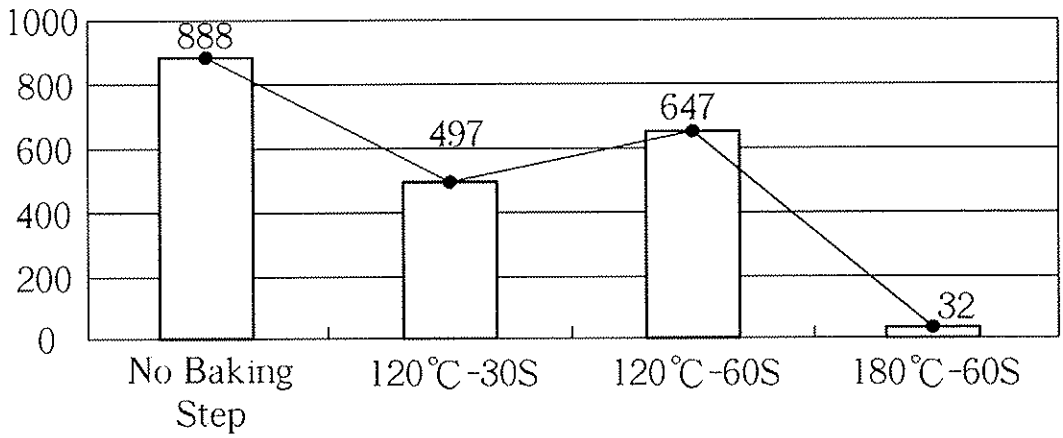

1000
800
600
400
200
0
888
497
647
32
No Baking Step
120℃-30S
120℃-60S
180℃-60S

FIG. 2

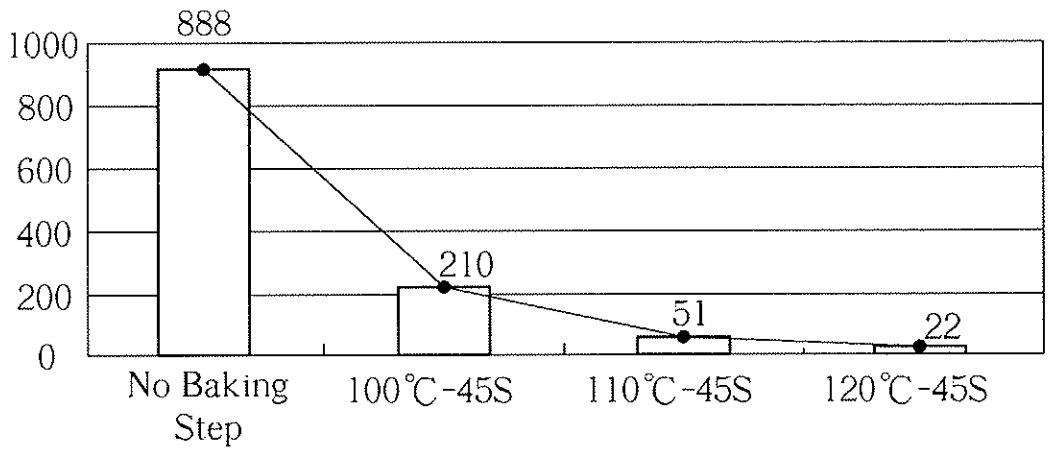

888
1000
800
600
400
200
0
210
51
22
No Baking Step
100℃-45S
110℃-45S
120℃-45S

FIG. 3

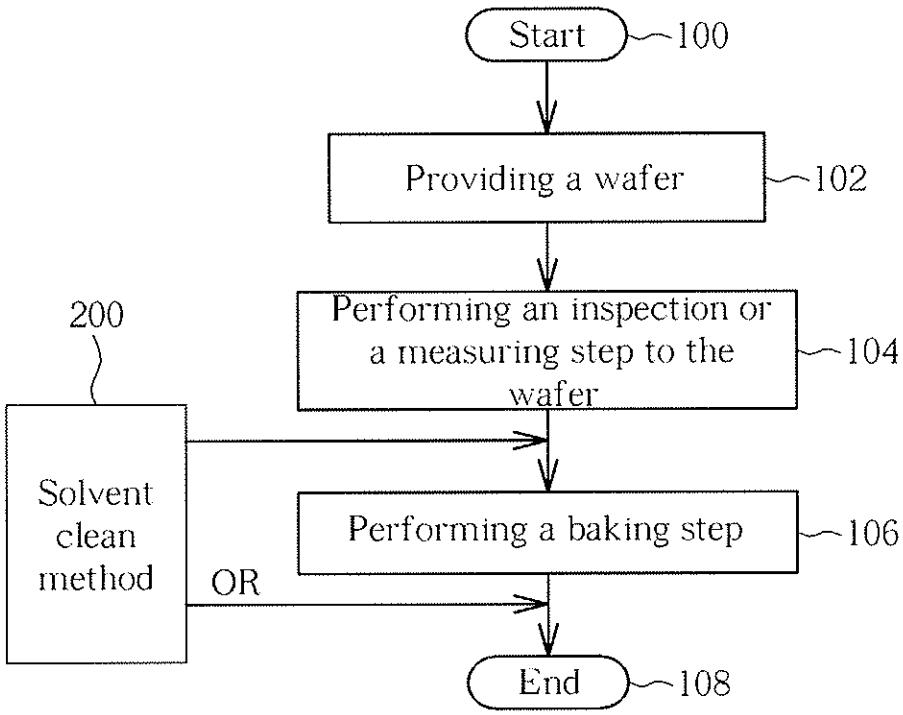

Start
100
Providing a wafer
102
Performing an inspection or a measuring step to the wafer
104
200
Solvent clean method
OR
Performing a baking step
106
End
108

FIG. 4

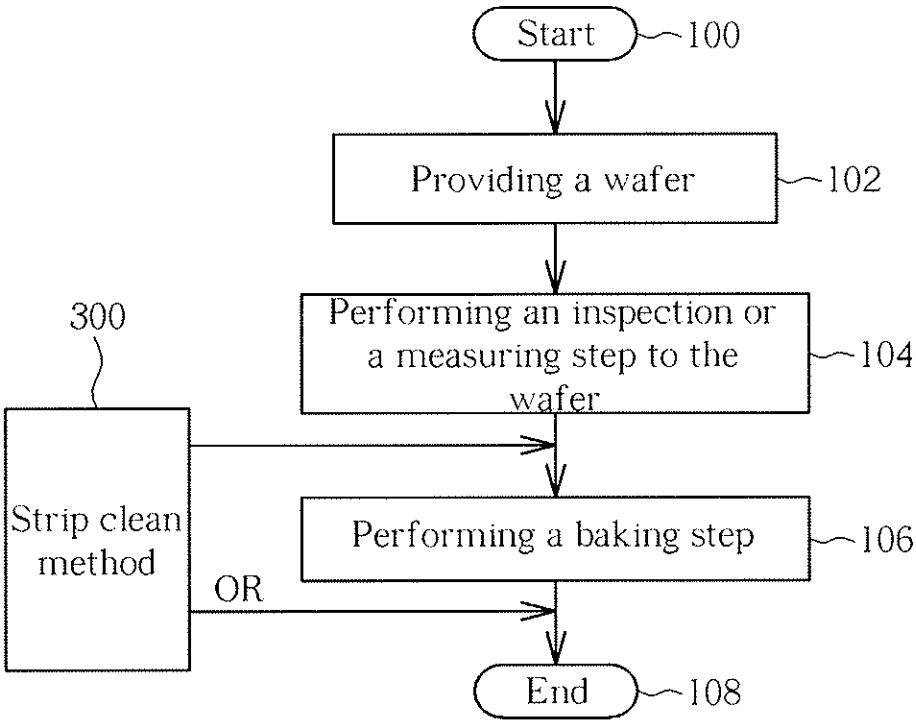

Start
100
Providing a wafer
102
Performing an inspection or a measuring step to the wafer
104
300
Strip clean method
OR
Performing a baking step
106
End
108

FIG. 5